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<u>Résumé</u>- Le présent travail concerne les réactions entre Si et ZrO_2 susceptibles d'intervenir pendant la nitruration du silicium et pouvant affecter les produits de réaction. Les essais d'analyse thermique, de dilatométrie et de diffraction des rayons X montrent que Si réagit avec ZrO_2 pour donner $ZrSiO_4$ et $ZrSi_{2-v}$:

 $2ZrO_{2} + (3-x)Si \longrightarrow ZrSiO_{4} + ZrSi_{2-x}$

Ultérieurement, la nitruration peut mener à une apparition de ZrN, $Zr_{7}O_{11}N_{2}$ et Si N₂O. Certains de ces composés (par ex. ZrN et $Zr_{7}O_{11}N_{2}$) pourraient diminuer la résistance à l'oxydation du matériau fritté.

<u>Abstract</u> - The present work addresses the interaction between Si and ZrO_2 which may occur during the nitridation stage of silicon and can affect the final reaction products. Using the thermoanalytical methods combined with X-ray diffractometry it has been shown that the Si, parallel to the nitride formation, disproportionates in the presence of ZrO_2 forming $ZrSiO_4$ and $ZrSi_2-x$ according to

 $2ZrO_2 + (3-x)Si \longrightarrow ZrSiO_4 + ZrSi_{2-x}$

It is shown further that these reaction products form ZrN, $Zr_2O_{11}N_2$ and $Si_2N_2O_1$ during the nitridation. ZrO₂ thus affects the nitridation so that less desirable by-products are introduced (i.e. ZrN, $Zr_2O_{11}N_2$) which may cause a decreased oxidation resistance of the sintered body.

I - INTRODUCTION

Increasing attention has been given in recent years to improving the strength and fracture toughness of ceramics by providing crack arresters in the ceramic matrix. Zirconia systems appear to be the most promising ones to study these phenomena. In partially stabilized zirconia (PSZ) the metastable tetragonal phase will transform to the monoclinic phase in the stress field of propagating cracks. This stress-induced transformation is assumed to provide the principal toughening mechanism in the PSZ. Zirconia is also being considered as a sintering aid for the fabrication of dense Si₂N₄-based ceramics. The emerging techniques (Sintered Reaction Bonded and Nitrided

Pressureless Sintered Silicon Nitride (SRBSN and NPS-technique))/1,2/ for fabrication of complex shapes of dense ${\rm Si}_3{\rm N}_4$ -based ceramics involve use of Si powder in the starting powder materials. In these new techniques it is of interest to mix the Si powder, before nitridation, with the sintering and/or toughening aids to get dense ${\rm Si}_3{\rm N}_4$ -based ceramics without posttreatments. In this work the interaction between ${\rm ZrO}_2$ and Si has been studied in both Ar and ${\rm N}_2$ atmosphere to elucidate the reaction sequence in this system.

II - EXPERIMENTAL METHODS

The	characteristi	cs of	the	starting	powders	are	given	below.
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Origin		Impurities (wt.%)	BET Spec.Surface area(m ² /g)
Si	Kema Nord AB	0.40 Fe ; 0.23 Al; 0.02 Ca	2.3
Zr0 ₂	Kebo Grave AB	p.a.	6.5

The powders were mixed in molar ratios $2rO_2:Si = 1:2 - 1:3$ in an agate mortar and powder compacts then were formed by uniaxial and isostatic pressing. Mettler thermoanalyzer TAI(TGA) and Harrop Dilatometer TD716 (TDA) were used to determine the mass and volumetric change, respectively. The dilatometric (TDA) curves were electronically compensated for the expansion of the alumina holder. The characteristic parameters were as follows: TGA sensitivity/range: 0.05 mg/100 mg; TDA sensitivity/range: $2\cdot10^{-4}$ mm per mm rec./1% per inch; gases used: N₂-SR, Ar-SR (nominal impurity content: less than 15 ppm); flow rate: ca 5 l/h. The phases were identified by X-ray powder diffractometry (XRD).

III - RESULTS AND DISCUSSION

1. Dilatcmetry, thermogravimetry and XRD.

Fig. 1 shows a dilatometric (TDA) curve for a $ZrO_2/2.5$ Si powder compact in an argon atmosphere. Above about 980 $^{\circ}C$ the compact is seen to start shrinking but at ca. 1200 $^{\circ}C$ the shrinkage is altered to expansion which recedes slowly up to 1450 $^{\circ}C$. The minimum on the TDA curve coincides with the m---> t-ZrO₂ phase transition temperature (1175 $^{\circ}C$ /3/).



Figure 1. Dilatometric (TDA) curve for a $ZrO_2/2.5$ Si (molar ratio) powder compact heated at 5 /min in an argon²atmosphere.

As shown in Table 1 the reaction products obtained at $1450^{\circ}C$ are $2rSiO_4$ and $2rSi_{2-x}$, the reaction is however not completed and some unreacted Si and $2rO_2$ is always left regardless of the $2rO_2/Si$ molar ratio.

Temperature (^O C) (cf. fig. 1)	Phases identified by XRD						
980 ⁰ 1150 ⁰ 1200 ⁰ 1300 ⁰ 1450 ⁰	Si " "	m-ZrO ₂ ""	ZrSiO ₄ " "	(traces) ^{ZrSi} 2-x "	sio ₂		

Table 1. Phases identified by XRD for ZrO_2/Si compacts heated (5 $^{\circ}$ min) to different temperatures in Ar atmosphere.

The XRD analysis of the specimens heated at 5° /min to the temperatures indicated in Table 1 gave the following picture of the reaction processes: At 980 C the incipient formation of $2rSiO_4$ suggests an initial reaction of $2rO_2$ and the surface silica on the Si particles. The increasing intensities for $2rSiO_4$ and the appearance of $2rSi_{2-x}$ at 1150 C indicate a reaction proceeding according to

 $2m-Zro_2 + (3-x)Si \longrightarrow ZrSio_4 + ZrSi_{2-x}$

At 1200 °C, which temperature is the turning point of the TDA curve, SiO₂ appears as a new phase and the relatively increasing intensity of $2rSi_{2-x}$ at 1300°C suggests that the main reaction is

 $t-ZrO_2 + (3-x)Si \longrightarrow ZrSi_{2-x} + SiO_2$.

At 1450 $^{\circ}$ C, however, the SiO₂ phase has disappeared and only ZrSiO₄ and ZrSi_{2-x} remain. TGA indicates a start of weight loss above 1200 $^{\circ}$ C. The disappearance of SiO₂ is thus probably due to the reaction of SiO₂ with residual Si (and perhaps even ZrSi_{2-x}) giving SiO(g).

TGA-followed nitridation of the products formed in Ar at 1450° C in N₂ gas starts at about 1200 °C giving ZrN, $Zr_7^{\circ}_{11}N_2$ /4/ and $Si_2N_2^{\circ}_{2}$.

Direct nitridation of the compacts starts at about $1150^{\circ}C$ and, in addition to the above products, alpha-Si₃N₄ is obtained.

It thus can be concluded that silicon disproportionates in the presence of ZrO_2 forming ZrSiO_4 and ZrSi_{2-x} as final products. The reaction seems to be initiated at a lower temperature or proceeds parallel to the nitridation of Si. The reaction sequence is as shown below.

 $\underset{N}{\text{si+zro}_{2} \xrightarrow{\text{Ar}} \text{zrsio}_{4} + \text{zrsi}_{2-x}(+\text{sio}_{2}) \xrightarrow{\text{N}_{2}} \text{zrn+zr}_{7} \circ_{11} N_{2} + \text{si}_{2} N_{2} \circ_{11} \circ_{11} \circ_{12} + \text{si}_{2} N_{2} \circ_{11} \circ_{12} + \text{si}_{2} \circ_{12} \circ_{1$

The intermittently released SiO(g) may favour the formation of alpha - $Si_{3}N_{4}$.

2. Thermodynamical features of the reactions

2.1 Volumetric changes

As shown in Fig. 1 the TDA curve indicates a change at about 1200° C from shrinkage to expansion for the reacting Si/ZrO₂ powder compacts.

This change coincides with (a) the appearence of SiO₂ as an intermediate phase and (b) the m \longrightarrow t-2rO₂ phase transition (Teq~1175°C). The chemical equation for the phases formed below 1200°C (Table 1) is

$$2ZrO_2 + (3-x)Si \longrightarrow ZrSiO_4 + ZrSi_{2-x}$$
 (

and corresponds to a change of molar volume $\Delta \bar{v} \sim -9.0$ % (for x = 0) and thus is consistent with the observed contraction. Above 1200°C formation of SiO₂ occurs. The summary equation of

$$3ZrO_2 + (6-x)Si \longrightarrow ZrSiO_4 + 2ZrSi_2 + SiO_2$$
 (2)

leads to $\Delta V \sim -6.4$ %, (x = 0) while, instead, an expansion is observed (Fig.1). Considering only the partial process of

$$z-ZrO_2 + (3-x)Si \longrightarrow SiO_2(trid.) + ZrSi_2$$
 (3)

the $\Delta \vec{V} \sim 0$ for x = 0 and will change to expansion for x >0 unless a significant contraction of the ZrSi₂ lattice occurs as a result of nonstoichiometry. No such evidence has been apparent from the XRD spectra. The expansion as observed in Fig.1 above 1200 °C will certainly be assisted by the transformation of m-ZrO₂ to the t-ZrO₂ of lower \vec{V} . (The above \vec{V} values are based on room temperature data and a significant difference of expansion coefficients for the phases involved may also be of importance in a rigorous treatment).

2.2 Free enthalpy changes

Table 2 below shows the thermodynamic data for the total reaction (1) and the partial reaction (2) with the intermediary SiO_2 formation.

T (K)	∆H(cal/mol)		∆S(cal	/mol K)	∆G(cal/mol)		
	(1)	(2)	(1)	(2)	(1)	(2)	
298	1.0.103	7.5.103	-0.4	0.9	1.1.10 ³	7.2·10 ³	
1400	$-0.9 \cdot 10^{3}$	$4.1 \cdot 10^{3}$	-3.2	-4.1	3.6·10 ³	$9.8 \cdot 10^{3}$	
1600	-3.8:10 ³	$-0.3 \cdot 10^{3}$	-5.2	-7.1	$4.5 \cdot 10^{3}$	11.1.10 ³	

Table 2. Thermodynamic data obtained /5/ for reaction (1) and (2).

As is apparent the ΔH and ΔS value for the total reaction is positive and negative, respectively, over the temperature range of 298-1600 K (25-1327°C). Thus according to the tabulated data there is no driving force for the reaction (1). For the reaction (2) including the formation of SiO₂ the ΔH is negative only at 1600 K but ΔS is still negative thus²giving positive ΔG (but much less positive than for the reaction (1)). The reaction (2) however still takes place. To an extent this discrepancy certainly reflects the lack of accuracy in the tabulated data but, at the same time, suggests that the driving force for this reaction is very low. This is consistent with the results of XRD showing that the reaction is never complete - residual Si and ZrO_2 is always present in a relatively significant amount.

Besides, if the reaction (2) gives $\text{ZrSi}_{2-\mathbf{x}}$ with x>0 the entropy on the left side will be lower and the entropy on the right side will be increased by a configurational term, due to the non-stoichiometry of $\text{ZrSi}_{2-\mathbf{x}}$. Thus the total Δ S term may turn positive and give a negative Δ G already at the temperature of the observed start of the $\text{ZrSi}_{2-\mathbf{x}}$ formation (980^oC (1253K), Fig. 1).

Formation of non-stoichiometric $2rSi_{2-x}$ is also consistent with the observed expansion above about $1200^{\circ}C$ (Fig.1).

IV - CONCLUSION

Pure zirconia reacts with silicon, the reaction being already initiated below 1000°C. This reaction seems to start at a lower temperature or occurs parallel to the silicon nitride formation. The products formed, $ZrSiO_4$ and $ZrSi_{2-x}$, give ZrN, $Zr_7N_1O_2$ and Si_2N_2O as by-products of nitridation. The introduction of these by-products may destroy the oxidation resistance of Si_3N_4 materials sintered with ZrO_2 .

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